



Hybrid Positioniersysteme für Picometer Auflösung mit Millimeter Stellbereich



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Motivation

- Wie groß ist ein Picometer?
 - Welche Applikationen gibt es?
 - Welche Actuatoren nutzen wir?
 - Wie kommen Meter lange Bewegung mit Picometer zusammen?
 - Beispiele
-
- Hybrid Actuatoren für lange Stellbereiche
 - Piezo und Lorentz Force Actuatoren

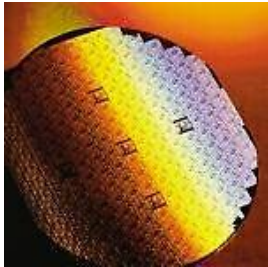
Wie groß ist ein Picometer?

- Klein gegenüber alltäglichen Abmessungen
- = 0.000 000 000 001m
- 1/60 000 000 Haardurchmesser
- 1/100 Atomradius Wasserstoffatom
- Groß gegenüber der Planck- Länge von 10^{-35} m





Picometer... für High-Tech Märkte ?



**Semiconductor
technology**



**Data storage
technology**



Microscopy



**Metrology /
laser systems**



**Life science /
biotech**



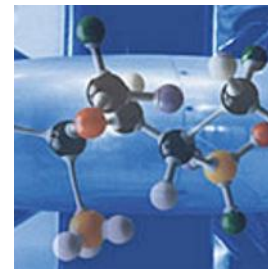
**Photonics/
optics**



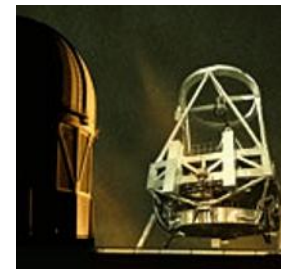
**Precision
machining**



**Automation /
handling**



**Nano-
technology**



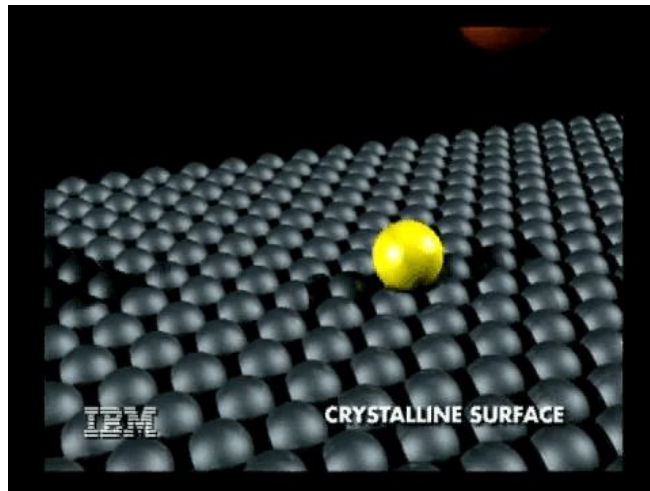
**Astronomy /
aeronautics**

Quelle: PI Katalog

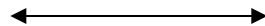
05.05.2011



Nanometer Size



1nm



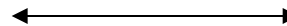
0,000 000 000 01 m

...

100's meter with nanometer accuracy



100m

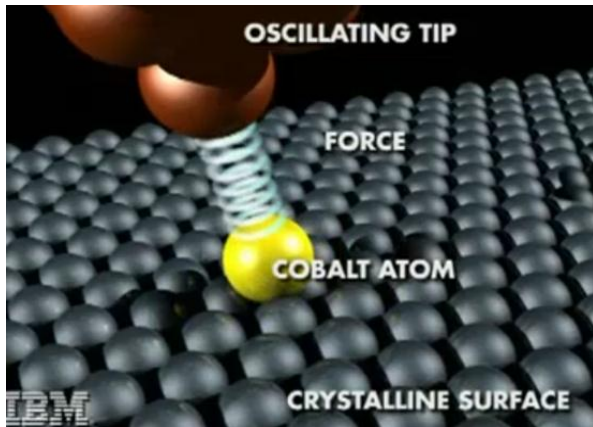


100m

LAMOST telescope / China



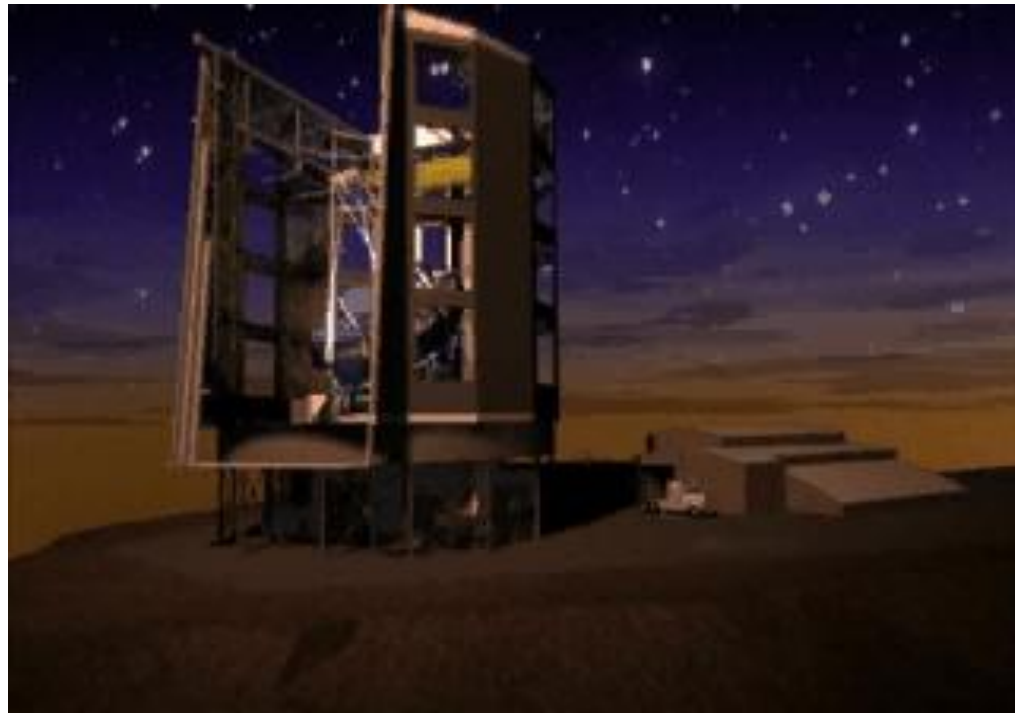
Nanometer Size



Quelle: IBM research

1nm

100's meter with nanometer accuracy



100m

Quelle: ESA

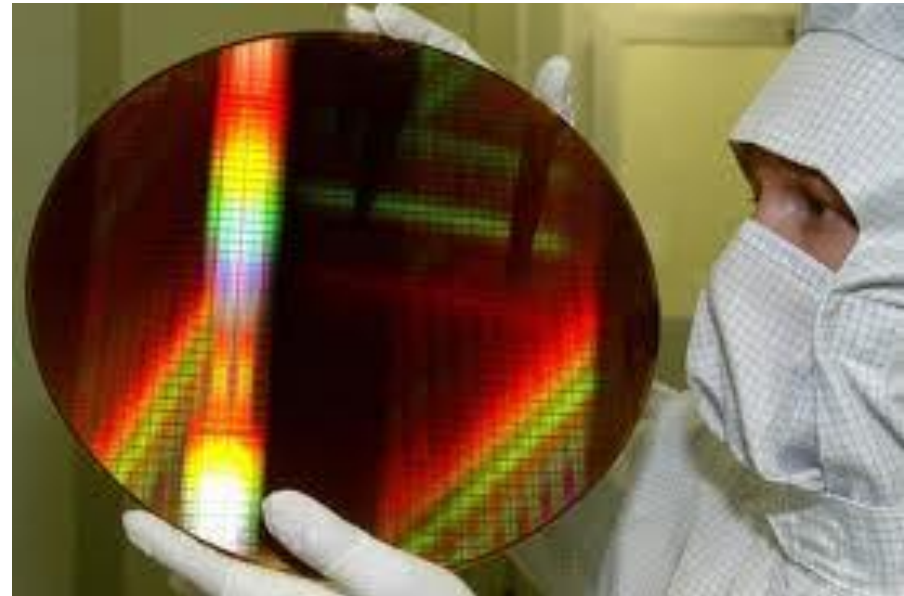
Author: Dr.Rainer Gloess | Page: 6



Nanometer or even Picometer Resolution in Semiconductor Technology

- Wafer stepper
- Wafer handling
- Reticle alignment
- Optics control
-

- Wafer inspection tools
- Optics inspection
- Reticle inspection
- Reticle repair
-

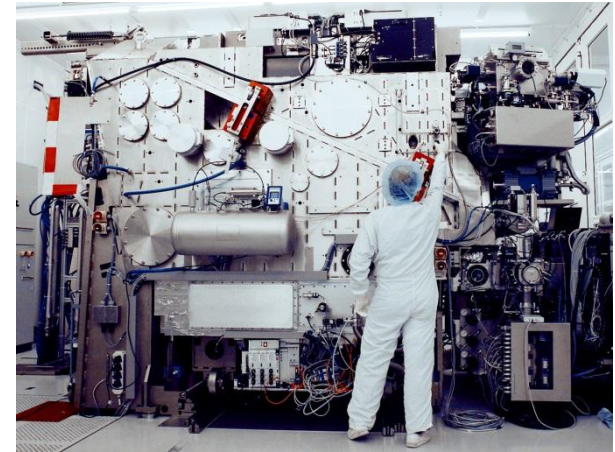


Quelle: welt.de

Roadmap of Wafer Stepper → EUVL



Quelle: ZEISS



Quelle: ASML



2006

ADT

Resolution = 32 nm
NA = 0.25, $\sigma = 0.5$
Overlay < 7 nm
Throughput 5 WPH



2010

NXE:3100

Resolution = 27 nm
NA = 0.25, $\sigma = 0.8$
Overlay < 4.5 nm
Throughput 60 WPH



2012

NXE:3300B

Resolution = 22 nm
NA = 0.32, $\sigma = 0.2-0.9$
Overlay < 3.5 nm
Throughput 125 WPH



2013

NXE:3300C

Resolution = 18/16* nm
NA = 0.32, OAI
Overlay < 3 nm
Throughput 150 WPH

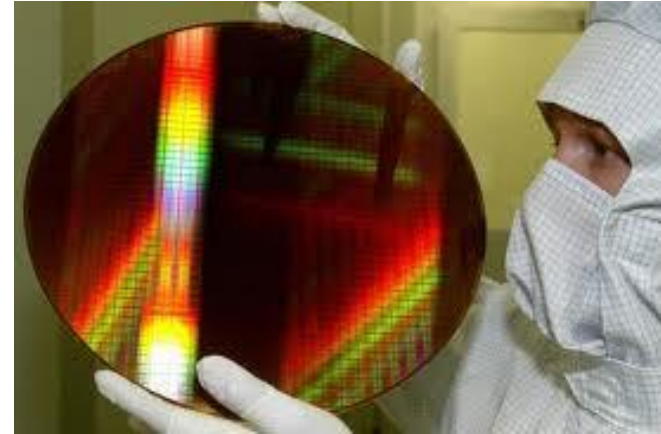
Quelle: ASML



Wo sind Positionierungen kleiner 1nm erforderlich?

- Beispiel:

- 12 "...15" Wafer



- Wafer 1mK Temperaturdifferenz beim Auflegen auf den Wafer- Chuck

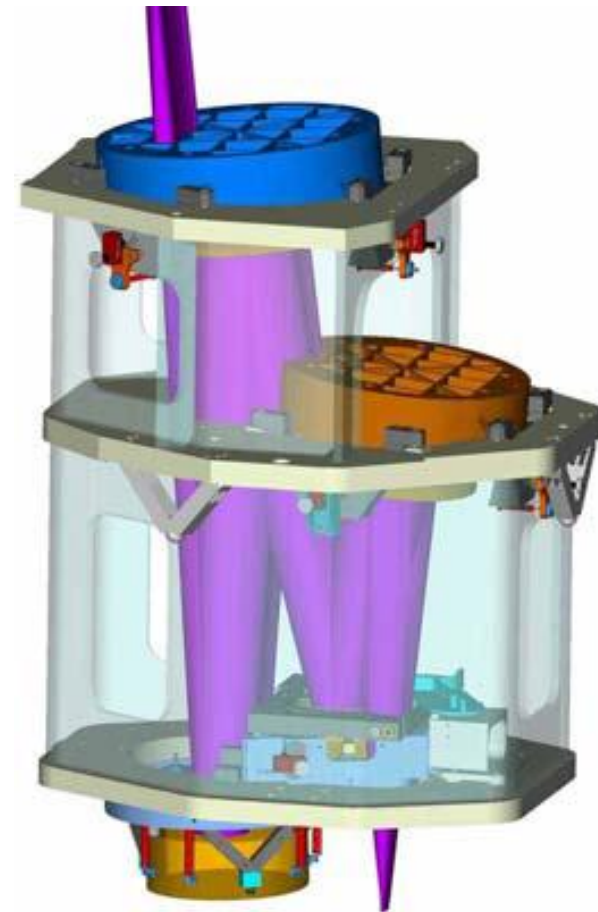
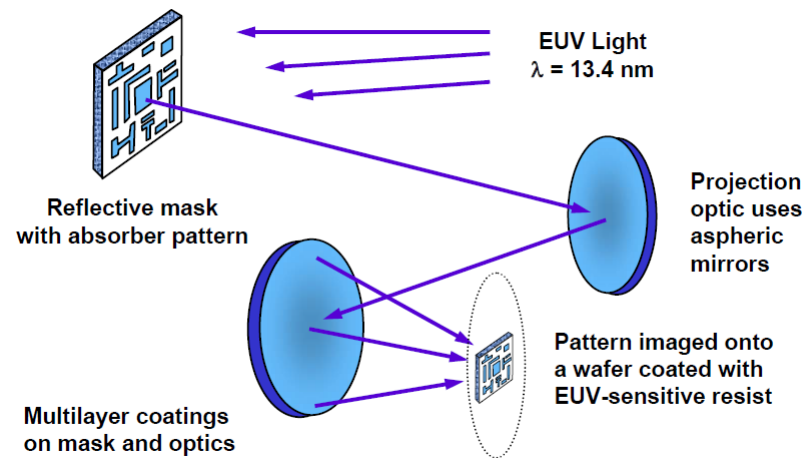
- Ausdehnungskoeffizient: Si $2,6 \cdot 10^{-6}$

- $300\,000\,000\text{nm} \cdot 2,6 \cdot 10^{-6}/\text{K} = 780\text{nm}$ Verformung /K
bei Aluminium ergeben sich ca. $7\mu\text{m}$ Verformung



< 1nm

- EUVL Optik 150pm
Absolutabweichungen von der
Parabolforn,
- 30pm Kurzwelligkeit

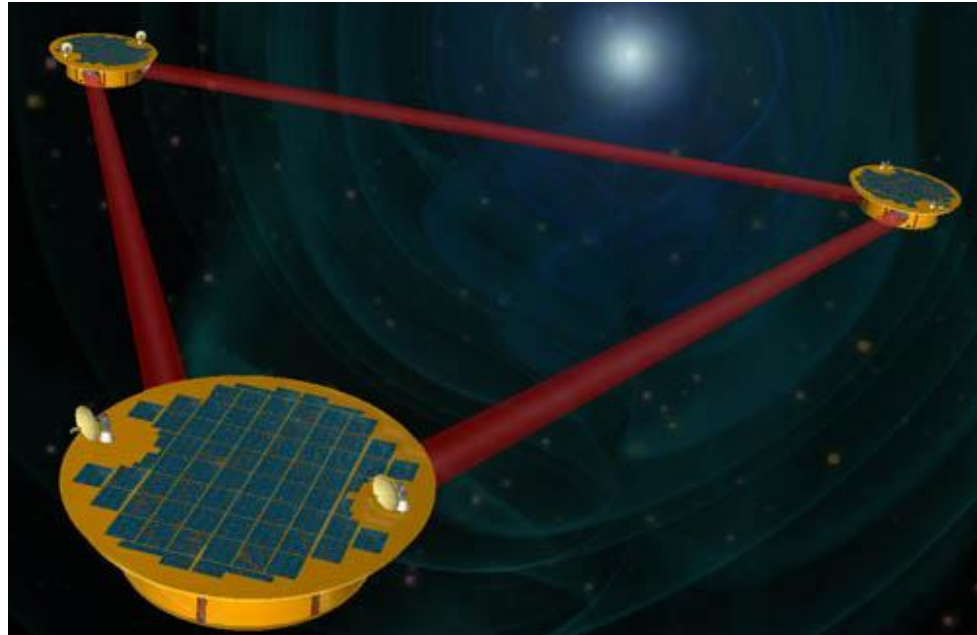


Quelle: ASPE 2009



< 1nm in kosmischen Dimensionen

- LISA
- NASA / ESA
- Gravitationswellen
Experiment 5Mio km ,
20pm Auflösung





PI's optischer inkrementaler Sensor

Basis: zwei Beugungsgitter

L x W x H = 23mm x 12mm x 9,5mm

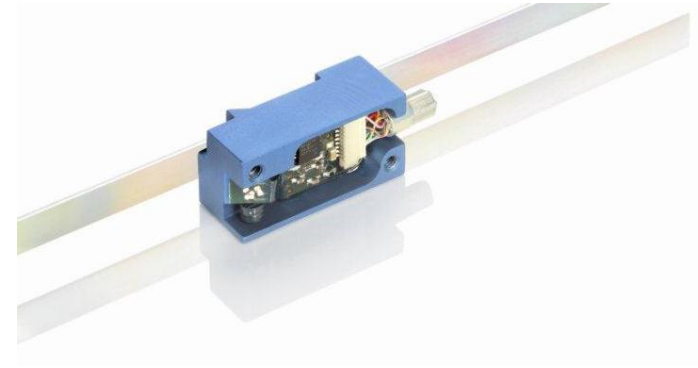
Bewegte Grating Periode 2 μm

Feststehende Grating Periode 1 μm

Signal Periode 0.5 μm

Laser 655nm (LP red)

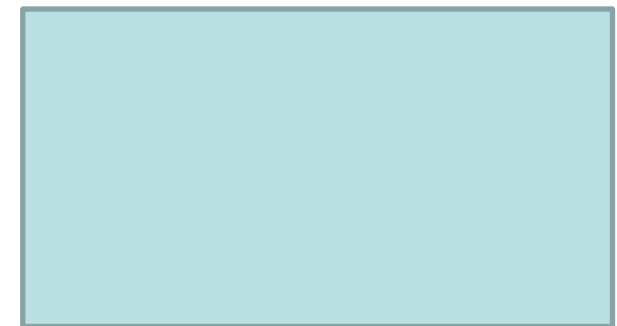
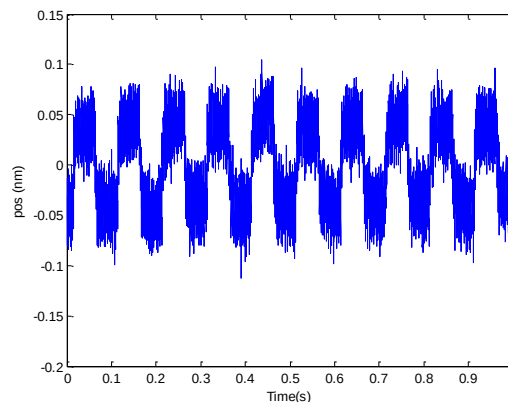
Auflösung < 20pm (Picometer) RMS



Mach-Zehnder interferometer

Beispiel:

100pm steps



Phasengitter



Piezo

vs.

Voice coil

- Steifigkeit
- Ladungsverschiebung → mechanische Verschiebung
- Leistungsloses Halten der Position
- Kann auch open loop gesteuert betrieben werden

- Steifigkeit gegen Null
- Strom → Kraft
- Leistungsverbrauch bei Gegenkraft
- Um Positionstabilität zu erreichen ist immer eine Regelung erforderlich
- (gilt auch für Reluktanz-Aktuatoren)



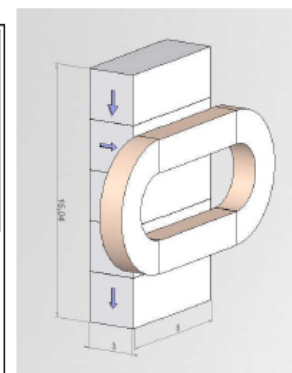
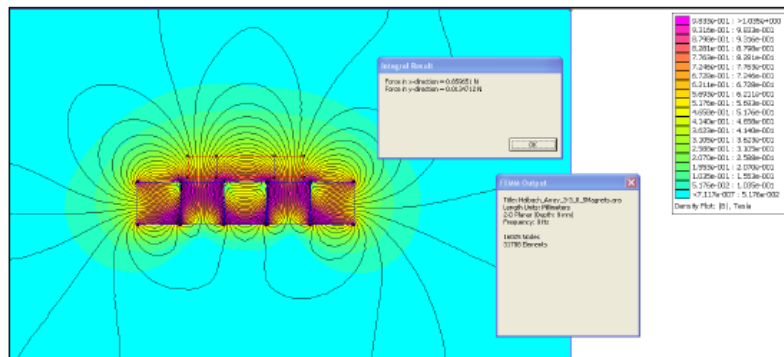
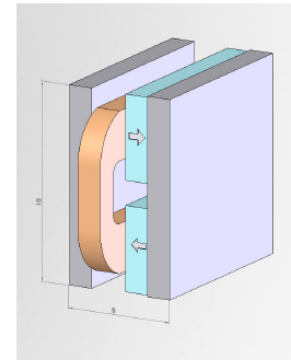
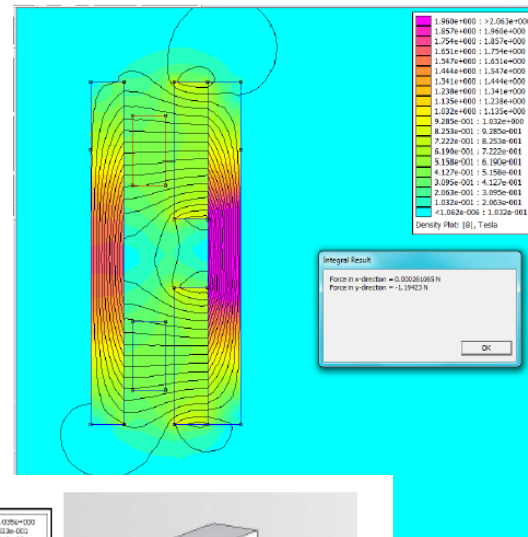
Welche Actuatoren sind für den Bereich $<1\text{nm}$ geeignet ?

- Piezo Stapel Aktuatoren
 - Piezo Bieger
 - Walk Drive Systeme, NEXLINE®
 - Lorentz Force (Voice Coil Aktuatoren)
 - Reluktanz- Aktuatoren
-
- Bedingt geeignet Ultrasonic Systeme



Magnetic Actuators

- Special design
- Free in design of magnet field structure

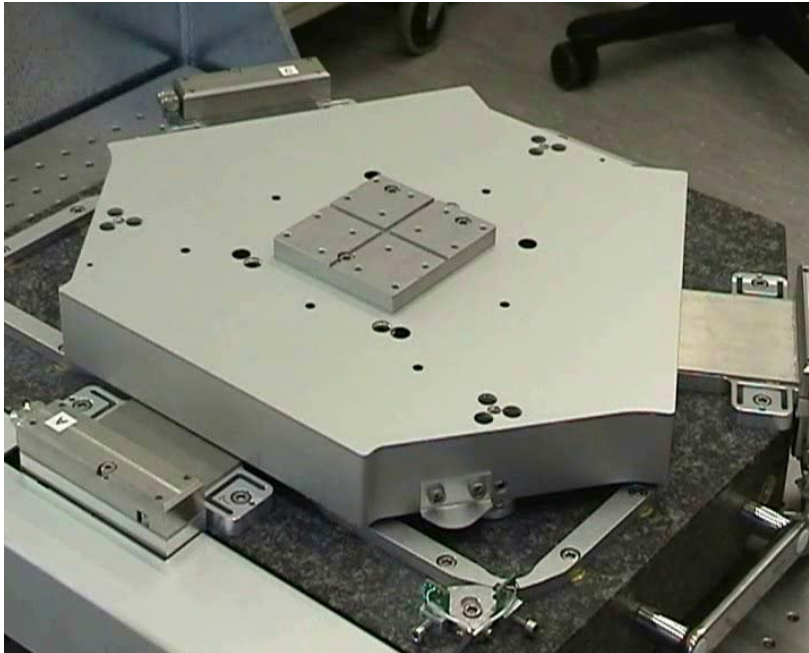


3 Magnets



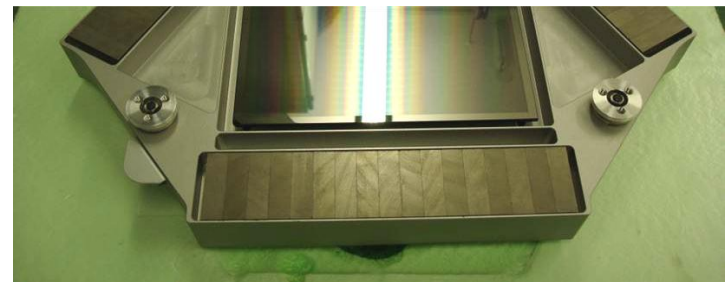
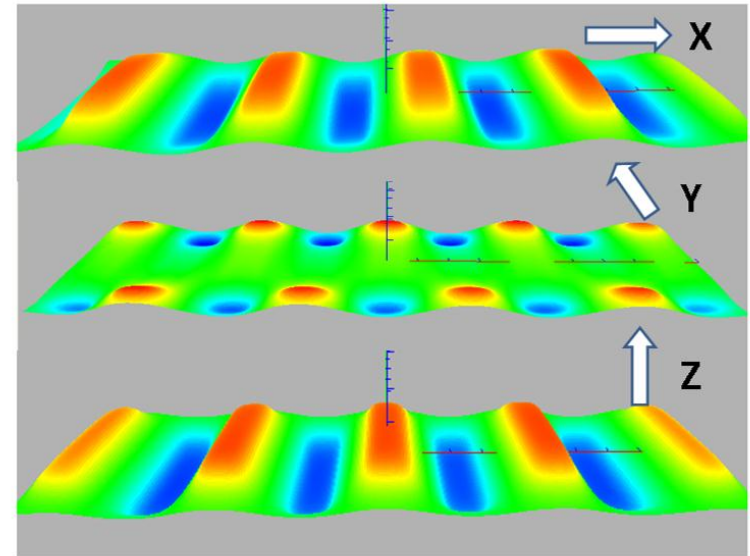
Halbach array

- Magnetic Levitation –
der fliegende Tisch



<http://www.youtube.com/watch?v=DQwqOYSzDI4>

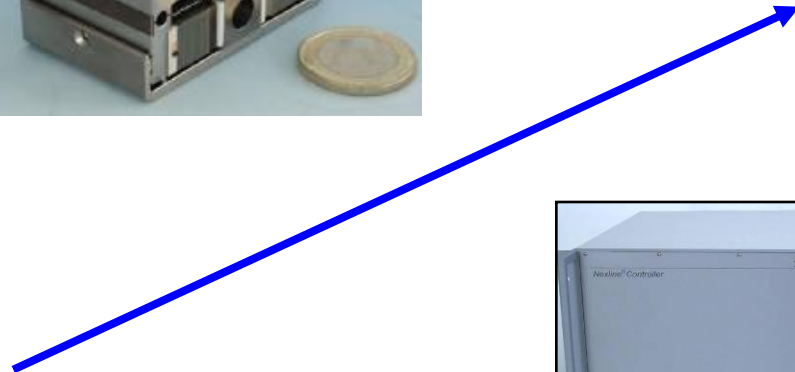
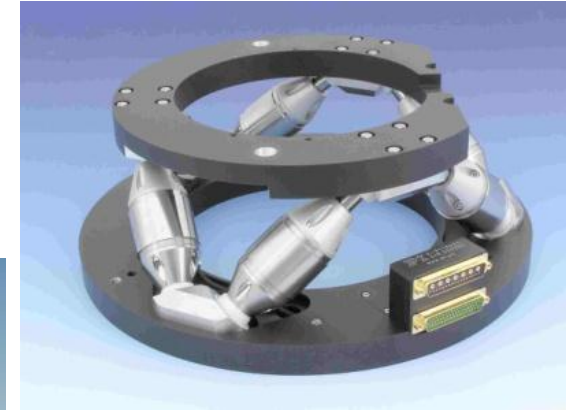
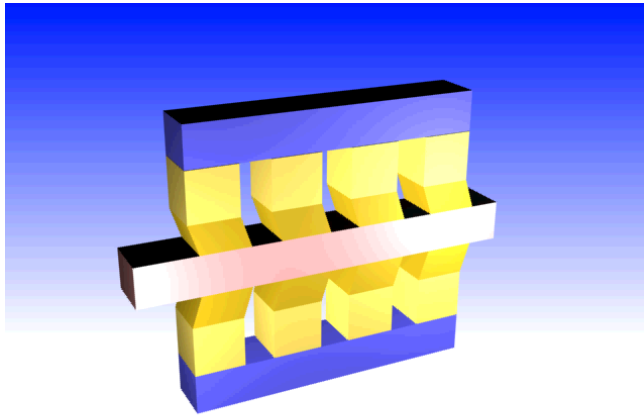
Flux density





Nicht magnetische Piezo Applikationen

- Piezo Walking Drive
- NEXLINE® oder NEXACT® Module

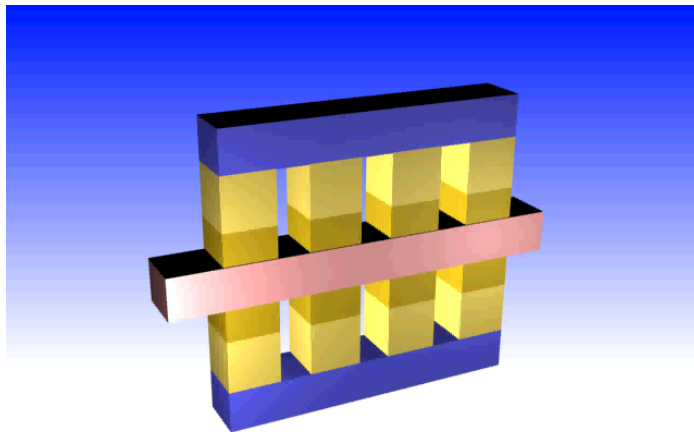
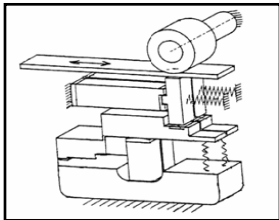




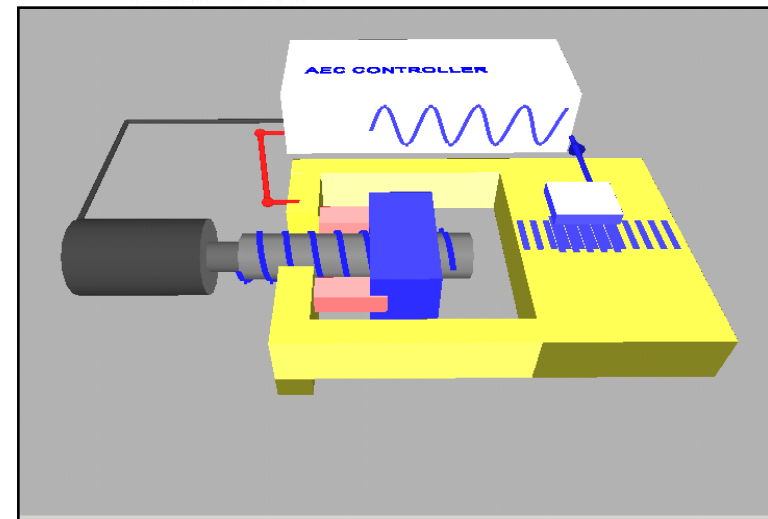
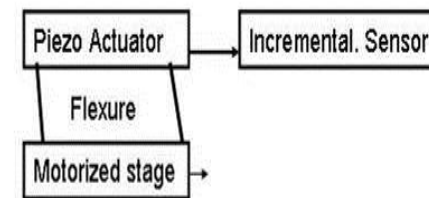
Hybrid System Design

Two Designs for Long-Travel Motion

Piezo Walking Drive



Piezo Hybrid Actuator

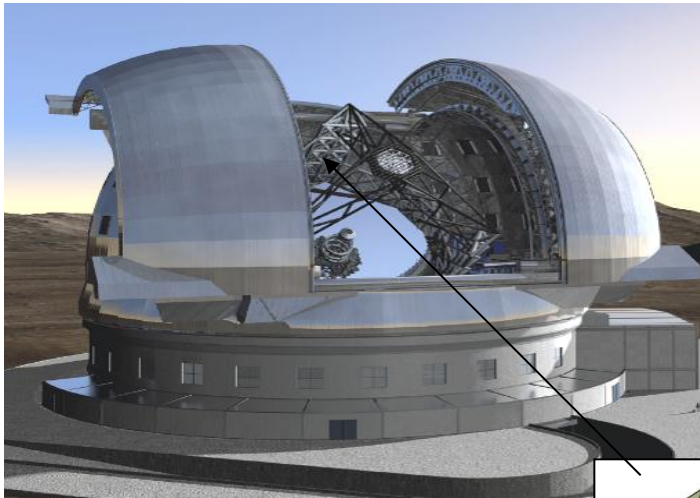




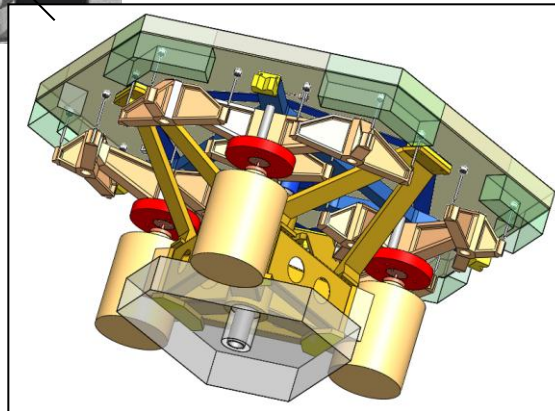
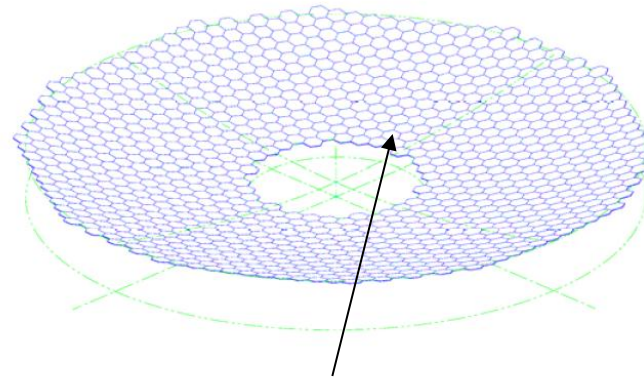
Hybrid positioning system

ESO: E-ELT Telescope

42m (39m) Primary mirror



100m



Hybrid= Motor
+Piezo

800 single mirror

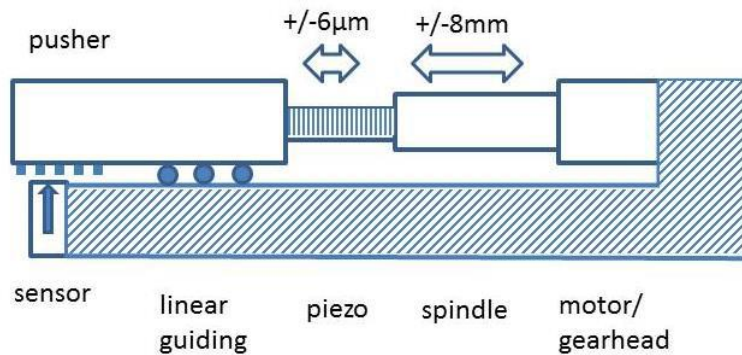


Hybrid mit zwei verschiedenen Actuatoren

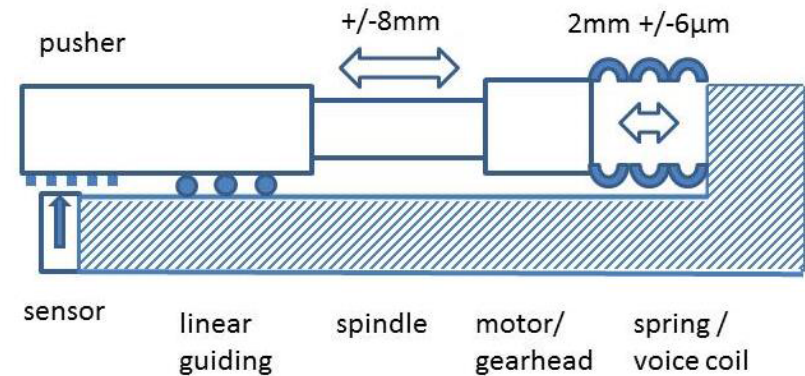
■ Piezo-Hybrid



Hermetisch
geschirmter Piezo



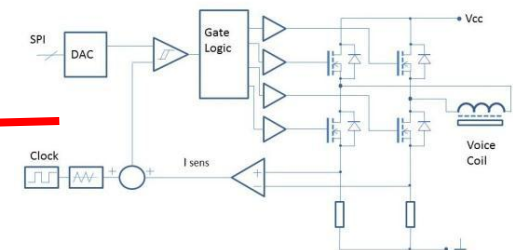
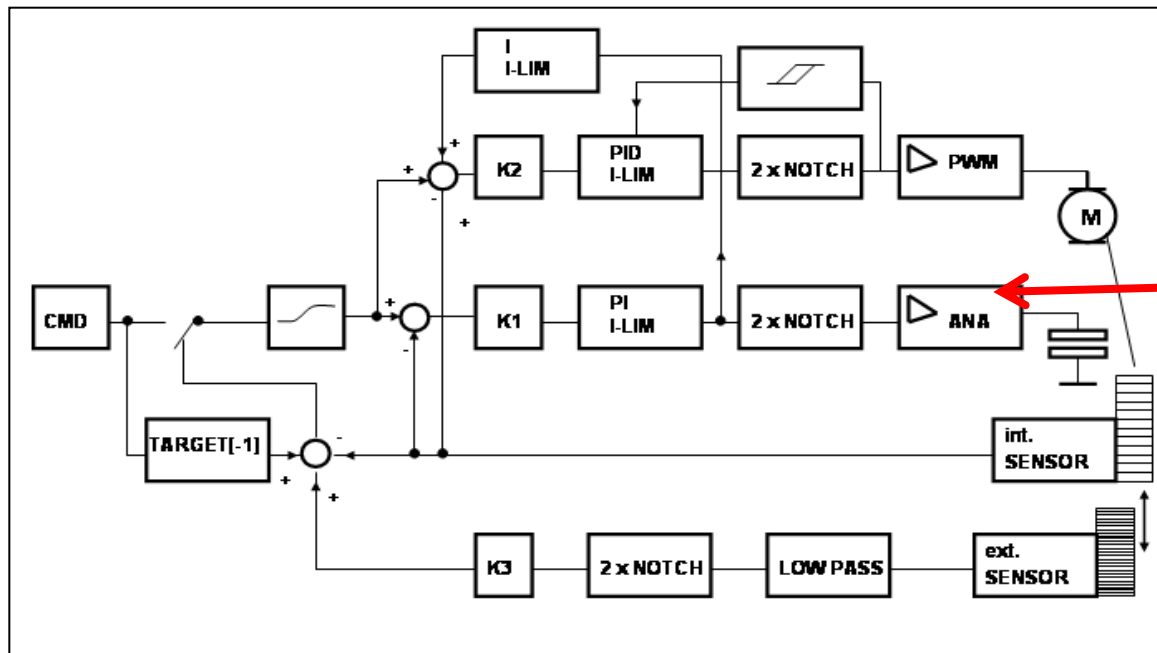
■ Lorentz-Force Hybrid





Hybrid Controller Firmware Structure

- Two independent separate control loops using a single incremental sensor
- Both control loops are always running
- Integral term coupling piezo loop to the motor loop to reduce the piezo voltage when the system is in position (statically)



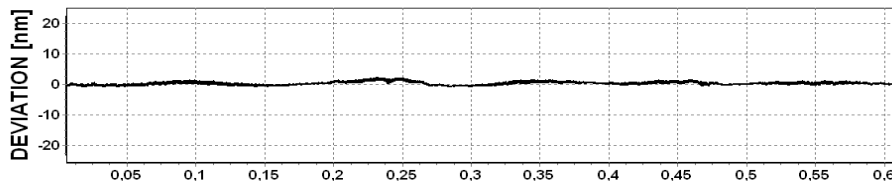
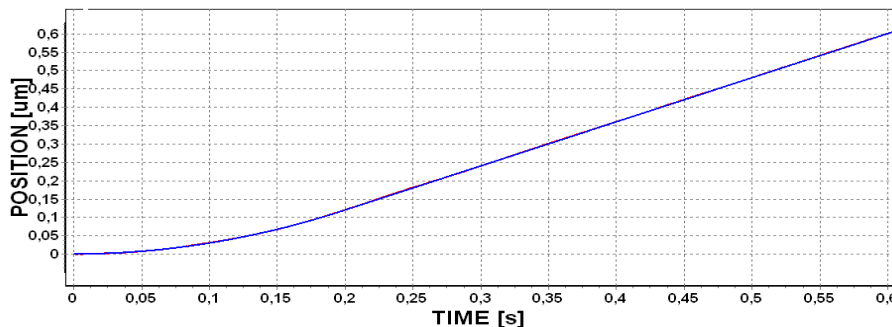
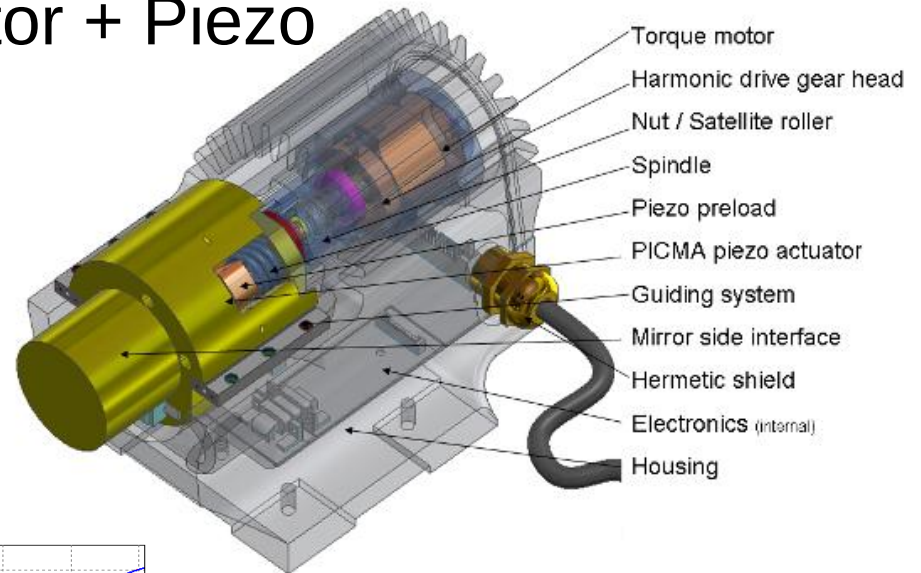
Current source for Lorentz Force Actuator

Hybrid Positionierer / Motor + Piezo

Requirements:

■ Travel range	15 mm
■ Load capacity	88 kg
■ Resolution	0.125 nm
■ Power dissipation	< 1W
■ Slewing	1.2 $\mu\text{m/s}$
■ Command sequence	1 kHz

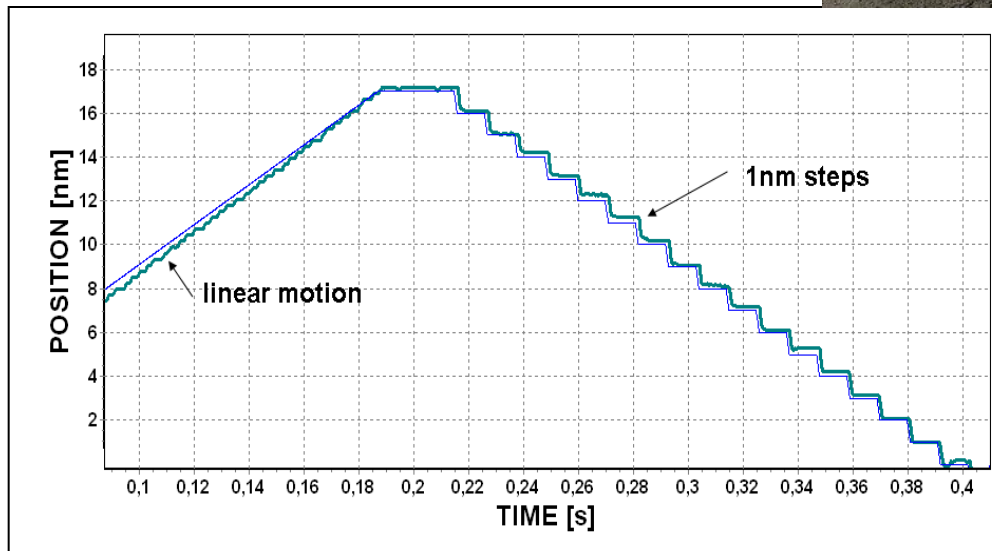
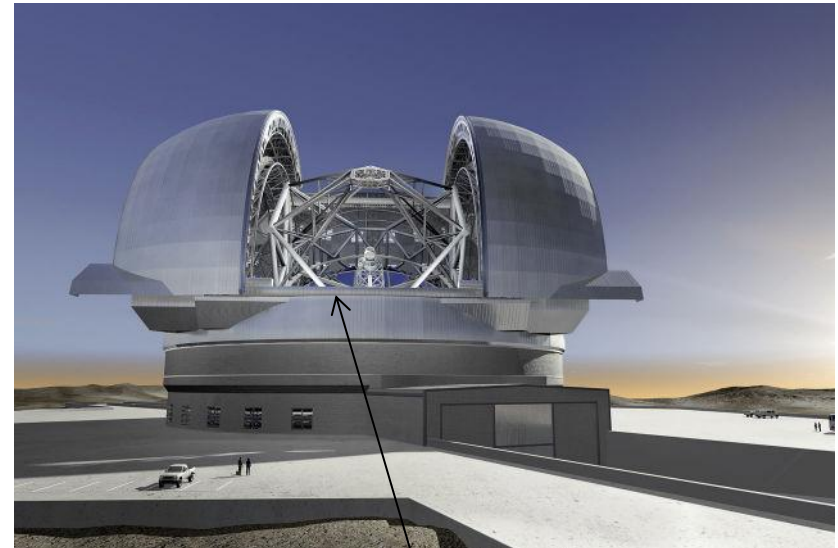
Tracking accuracy: <1nm





Hybrid Positionierer

Für große Systeme	100m
Stahlkonstruktion	3350t
Bewegte Optomechanik	755t
Für mittlere Stellwege	15mm
Hohe Auflösung	125pm



2400 x





Vielen Dank für Ihre Aufmerksamkeit



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